

## Investigation of strained-Sb Hetrostructures with high hole mobility

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**Background:** III-V semiconductors are one of the most promising device candidates for future high-speed, low-power logic applications due to their high electron mobility. Recently, high performance III-V n-FETs have been demonstrated [1]. However, for CMOS logic, there is a significant challenge of identifying high mobility III-V p-FET candidates [2]. Biaxial strain can be easily introduced in III-V hetrostructures during MBE growth. Biaxial strain splits the degeneracy between light hole (*lh*) & heavy hole (*hh*) bands reducing the transport effective mass ( $m^*$ ) and number of states available for interband scattering thereby enhancing hole mobility ( $\mu_h$ ). Percentage of strain induced (%), Valence Band Offset (VBO) for confining the 2 Dimensional Hole Gas (2DHG), modulation doping, dominant scattering limiting  $\mu_h$ , reduction of  $m^*$  with strain are some of the parameters that need to be investigated for achieving high hole mobilities in III-V's.

**Introduction:** In this paper we first use modeling to compare  $\mu_h$  and its enhancement with strain in As's and Sb's. Sb hetrostructures based on two different approaches are analyzed. Strain is quantified using high resolution XRD analysis, XPS analysis is used to estimate VBO's. Temperature Dependent Hall measurements are performed to identify the dominant scattering mechanisms. Finally effective mass ( $m^*$ ) and its reduction with strain is quantified using Shubnikov-de Haas oscillations.

**Modeling:** Band Structure using 8 band k.p [2] + Kubo-greenwood approach is used to calculate  $\mu_h$  in  $\text{In}_x\text{Ga}_{1-x}\text{As}$  and  $\text{In}_x\text{Ga}_{1-x}\text{Sb}$  (Sheet Charge ( $N_s$ ) =  $10^{12}/\text{cm}^2$ ). Sb's have ~2X higher  $\mu_h$  than As's (Fig. 1(inset)). Enhancement with biaxial strain is calculated using 8x8 Hamiltonian with Spin Orbit coupling [2]. We observe compression is better than tension (Fig. 1) & % mobility enhancement with strain is similar for As's & Sb's (~2.2X with 2% compression). But strained Sb's have much higher mobilities due to their higher unstrained mobility values. Sb channels with biaxial compression are optimal for achieving high  $\mu_h$ .

**Hetrostructure Design & Details:** Looking at the Bandedges vs. Lattice constants (Fig. 2) there can be 2 possible approaches for achieving biaxial compression in Sb channels i.e (A) using  $\text{In}_x\text{Ga}_{1-x}\text{Sb}$  channel and  $\text{Al}_y\text{Ga}_{1-y}\text{Sb}$  barrier. Compression in high Ga%,  $\text{In}_x\text{Ga}_{1-x}\text{Sb}$  channel is not possible using this approach & the maximum VBO is ~0.39eV. Approach (B) uses binary GaSb channel with  $\text{AlAs}_x\text{Sb}_{1-x}$ . This gives a higher VBO for confining the 2DHG & use of a binary channel avoids alloy scattering. We investigate Hetrostructures with  $\text{In}_{0.41}\text{GaSb}$  channels (approach A) and GaSb channels (approach B) grown using MBE on semi-insulating GaAs (100) substrate (Fig. 3). The  $\text{AlAs}_x\text{Sb}_{1-x}$  for approach B is grown as superlattice of AlAs & AlSb [3]. Table 4 lists the samples investigated, details of the growth procedures are summarized in [3-4].  $\text{In}_{0.41}\text{GaSb}$  channels are modulation-doped with Be after channel growth and GaSb channels are modulation-doped with Be prior to channel growth (Fig. 3).

**Strain:** High resolution XRD analysis is used to quantify strain. Fig. 4 shows the rocking XRD curves near the (004) GaAs peak for sample A1 ( $\text{In}_{0.41}\text{GaSb}$  channel) & sample B1 (GaSb channel with superlattice of  $(\text{AlAs})_x\text{AlSb}_{1-x}$ ). For sample A1 (Fig. 4 (a)) peaks are visible for the  $\text{InGaSb}$  channel,  $\text{AlGaSb}$  barrier and the GaAs substrate. For sample B1 (Fig. 4 (a)) we see the main and satellite

peaks for the digital superlattice ( $n=-1,0,\text{and}+1$ ), the 100nm AlSb buffer layer and the GaAs substrate (Fig. 4(b)). The GaSb channel peak gets buried in the satellite peak from the superlattice. Thickness for the AlSb & AlAs are determined by matching the XRD results with simulations and the  $\text{AlAs}_x\text{Sb}_{1-x}$  ternary composition is calculated using Vegard's law; Table 1 summarizes the results. Complete relaxation for the superlattice & the 100nm AlSb layer yields a good match to the peak position in the rocking curve, this is further confirmed by a reciprocal lattice scan around the (004) & (115) reciprocal lattice points (Fig. 5). The epilayer peaks are all broadened compared to the simulation. This is a result of a high density of misfit dislocations required to relax the high 7-8% lattice mismatch with substrate.

**VBO:** Citric acid based etch is used to selectively remove the InAs capping layer, a HCl solution based timed etch is then used to etch the subsequent Sb layers (Fig. 3). VBO is calculated (Fig. 6) by taking the difference between VB spectrum from channel and barrier (~0.3eV for A1 and ~0.6eV for B1). Ga 3d & In 4d peaks are used for reference.  $\text{SbO}_x$  formation & Sb accumulation on the surface after etching is also observed and will be discussed elsewhere. Higher VBO is achieved using the  $\text{AlAs}_x\text{Sb}_{1-x}$  barrier (approach B) as compared with  $\text{In}_y\text{Al}_{1-y}\text{Sb}$  (approach A).

**$\mu_h$ :** Hall measurements are performed on the samples varying temperature from 2K-300K. Fig. 7 summarizes the  $\mu_h$  &  $N_s$  values. For samples A1, A2 & B1 a  $T^{-3/2}$  temperature dependence in  $\mu_h$ , characteristic of polar optical scattering (which is the dominant mechanism limiting hole mobility at room temperature (RT) [5]) is seen from 200-300K. In GaSb sample B1, a  $T^{-1/2}$  temperature dependence characteristic of piezoelectric scattering (dominant in GaSb at low temperatures [5]) is also seen from 100-200K. Sample B2, B3 exhibit lower RT  $\mu_h$  & maximum  $\mu_h$  and a  $T^{-1}$  temperature dependence characteristic of mobility limited by interface defects [5].  $N_s$  vs. T is fairly constant as expected in modulation doping. Sample B2 and B3 exhibit slight  $N_s$  freeze out at low T again suggesting poor interface/dislocation as a result of strain relaxation in these samples.  $\mu_h$  saturates to a maximum value at low temperature in A1, A2 (modulation doped from top) while a dip in mobility at low temperature is seen in sample B1-B3 (modulation doped from bottom) due to dopant diffusion in the channel in latter samples causing coulombic scattering.

**$m^*$ :** Shubnikov-de Haas (SdH) oscillations (Fig. 8) are observed in samples A1, A2 & B1 at low temperature (2-20K) and high magnetic fields (0-9 Tesla) confirming good crystal & interface quality while no oscillations are seen in B2 & B3. Effective mass is extracted from the temperature dependence of SdH oscillations [6]. Table. 2 summarizes the results:  $m^*$  in bulk  $\text{In}_{0.41}\text{GaSb}$  & GaSb, results from modeling &  $m_{\text{min}}^*$  when the *lh* and *hh* become completely non-interacting are also listed for comparison. Results from SdH are confirmed using Cyclotron resonance in sample A1.

**Summary:** Maximum mobility of  $980\text{cm}^2/\text{Vs}$  at RT ( $N_s=1.2 \times 10^{12}/\text{cm}^2$ ) is achieved. Strain results in significant reduction of  $m^*$ . RT  $\mu_h$  is limited by interface scattering when strain gets relaxed & polar optical scattering otherwise

<sup>1</sup>B. R. Bennett et. al. Solid-State Electron. 49,1875 <sup>2</sup>A.T.B. Bahder et. al., PR-B, 41, 11992 <sup>3</sup>B. R. Bennett et. al. J Cryst Growth, 311, 47. <sup>4</sup>B. R. Bennett et al, APL, 91, 042104 <sup>5</sup>J. D. Wiley, Semiconductor and Semimetals, 10, 91 <sup>6</sup>T.E. Whall et. al, APL, 64, 357

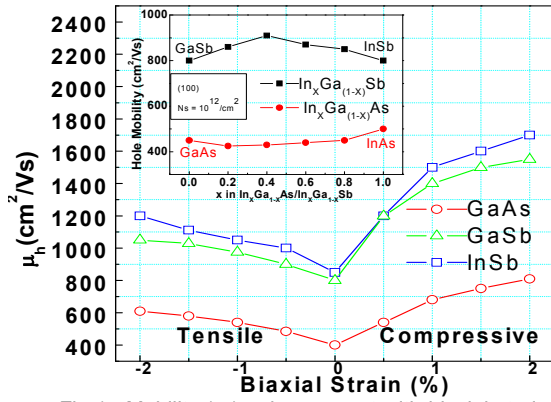


Fig.1. Mobility ( $\mu_h$ ) enhancement with biaxial strain (inset) Calculated  $\mu_h$  for  $\text{In}_x\text{Ga}_{1-x}\text{Sb}$  &  $\text{In}_x\text{Ga}_{1-x}\text{As}$ .

Sample	Channel	Barrier	Strain (%)	VBO (eV)	$N_s(\text{cm}^{-2})$ (300K)	$\mu_h(\text{cm}^2/\text{Vs})$ (300K)	$\mu_{\text{max}}(\text{cm}^2/\text{Vs})$
A1	$\text{In}_{0.41}\text{Ga}_{0.59}\text{Sb}$ (75Å)	$\text{Al}_{0.7}\text{Ga}_{0.3}\text{Sb}$	1.85	0.3	$1.2 \times 10^{12}$	960	4500
A2	$\text{In}_{0.41}\text{Ga}_{0.59}\text{Sb}$ (75Å)	AlSb	2.0	0.39	$9 \times 10^{11}$	900	5000
B1	GaSb (75Å)	$\text{AlAs}_{0.22}\text{Sb}_{0.78}$	1.06	0.56	$1.75 \times 10^{12}$	880	4400
B2	GaSb (75Å)	$\text{AlAs}_{0.24}\text{Sb}_{0.76}$	1.48	0.58	$1.60 \times 10^{12}$	690	1500
B3	GaSb (100Å)	$\text{AlAs}_{0.27}\text{Sb}_{0.73}$	1.22	0.6	$1.85 \times 10^{12}$	600	1000

Table.1: Summary of samples.

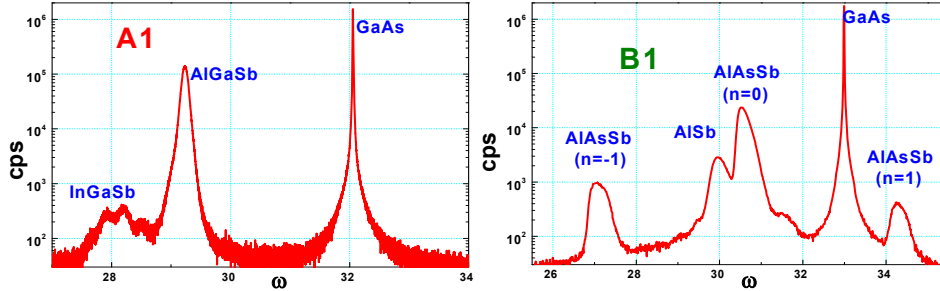


Fig.4. High Resolution XRD scans on the samples A1 (left) & B1 (right) near (004) GaAs peak.

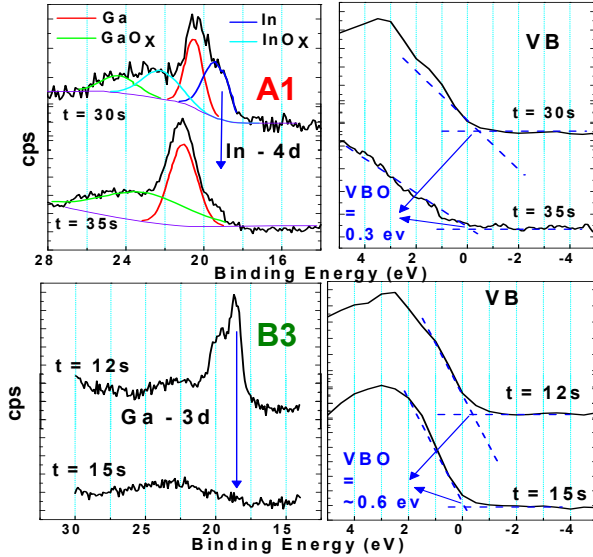


Fig 6. VBO offsets are estimated using high resolution XPS (Sample : A1 (top), B3 (bottom))

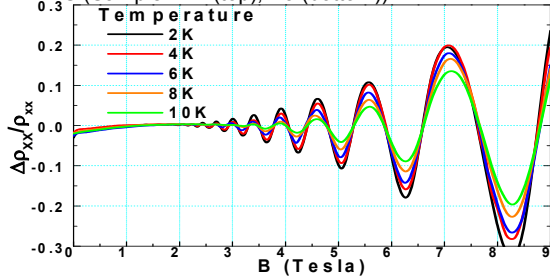


Fig.8. Temp dependence of Shubnikov-de Hass oscillations (above : A1) is used to calculate  $m^*$

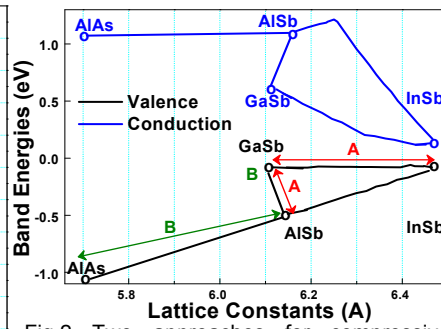


Fig.2 Two approaches for compressively strained Sb channel : (A) using  $\text{In}_x\text{Ga}_{1-x}\text{Sb}$  channel &  $\text{Al}_y\text{Ga}_{1-y}\text{Sb}$  barriers. (B) GaSb channel &  $\text{AlAs}_x\text{Sb}_{1-x}$  (superlattice of  $(\text{AlAs})_x(\text{AlSb})_{1-x}$ ) as barrier (see text).

A	B
InAs 2nm	InAs 2nm
$\text{In}_{0.2}\text{Al}_{0.8}\text{Sb}$ 4nm	$\text{In}_{0.2}\text{Al}_{0.8}\text{Sb}$ 4nm
$\text{Al}_{0.7}\text{Ga}_{0.3}\text{Sb}$ (Be) 5nm	$\text{AlAs}_x\text{Sb}_{1-x}$ 10.5nm
$\text{Al}_{0.7}\text{Ga}_{0.3}\text{Sb}$ 21nm	GaSb 7.5/10nm
$\text{In}_{0.41}\text{Ga}_{0.59}\text{Sb}$ 7.5nm	$\text{AlAs}_x\text{Sb}_{1-x}$ 10.5nm
	$\text{AlAs}_x\text{Sb}_{1-x}(\text{Be})$ 4.5nm
$\text{Al}_{0.7}\text{Ga}_{0.3}\text{Sb}$ 1.5μm	$\text{AlAs}_x\text{Sb}_{1-x}$ 1μm
	AlSb 0.1μm
	GaAs 0.1μm
SI GaAs substrate	SI GaAs substrate

Fig.3. Hetrostructures based on approaches (A) & (B). Growth details in [3-4]

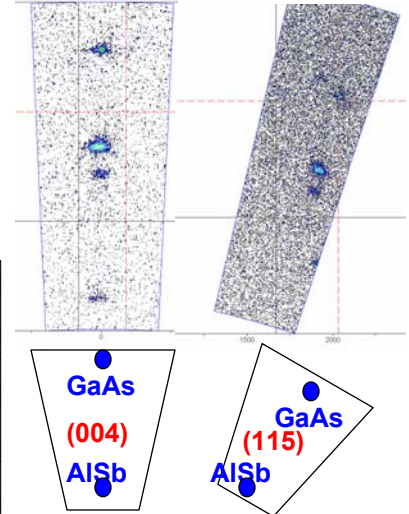


Fig.5. Reciprocal Lattice scan on sample A1 around (0 0 4) left & (1 1 5) right.

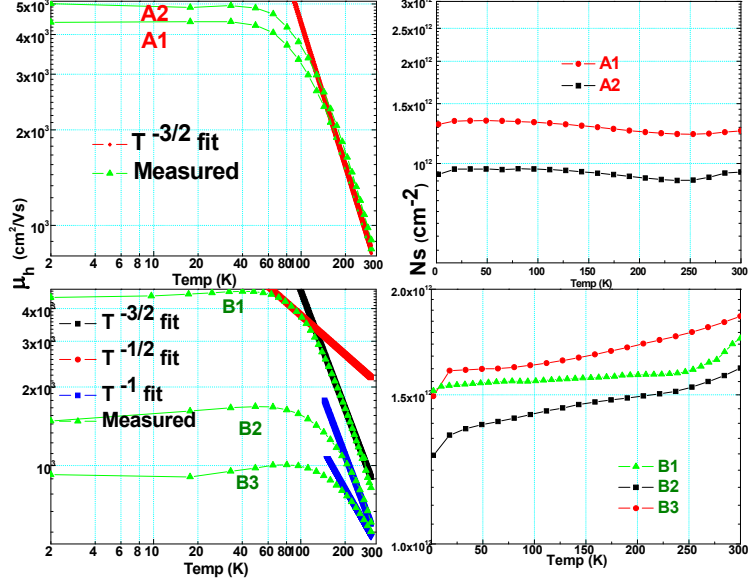


Fig 7.  $\mu_h$  and  $N_s$  as function of Temp. for sample A1-A2 (top) & B1-B3 (bottom).

Sample	Channel	Strain (%)	$m^*$
Bulk	$\text{In}_{0.41}\text{Ga}_{0.59}\text{Sb}$	0	0.40
A1	$\text{In}_{0.41}\text{Ga}_{0.59}\text{Sb}$	1.85	$0.099 \pm 0.02$ (SdH), 0.09 (k.p)
A2	$\text{In}_{0.41}\text{Ga}_{0.59}\text{Sb}$	2.0	$0.0946 \pm 0.01$ (SdH), 0.085 (k.p) 0.096 (Cyclotron resonance)
Max	$\text{In}_{0.41}\text{Ga}_{0.59}\text{Sb}$	Maximum	0.06 (k.p = $1/(\gamma_1 + \gamma_2)$ )
Bulk	GaSb	0	0.35
B2	GaSb	1.06	0.12 (SdH), 0.1 (k.p)
Max	GaSb	Maximum	0.07 (k.p = $1/(\gamma_1 + \gamma_2)$ )

Table.2:  $m^*$  with strain : Extracted value from oscillations (SdH), results from modeling (k.p) & verification with Cyclotron resonance